

FIG. 1

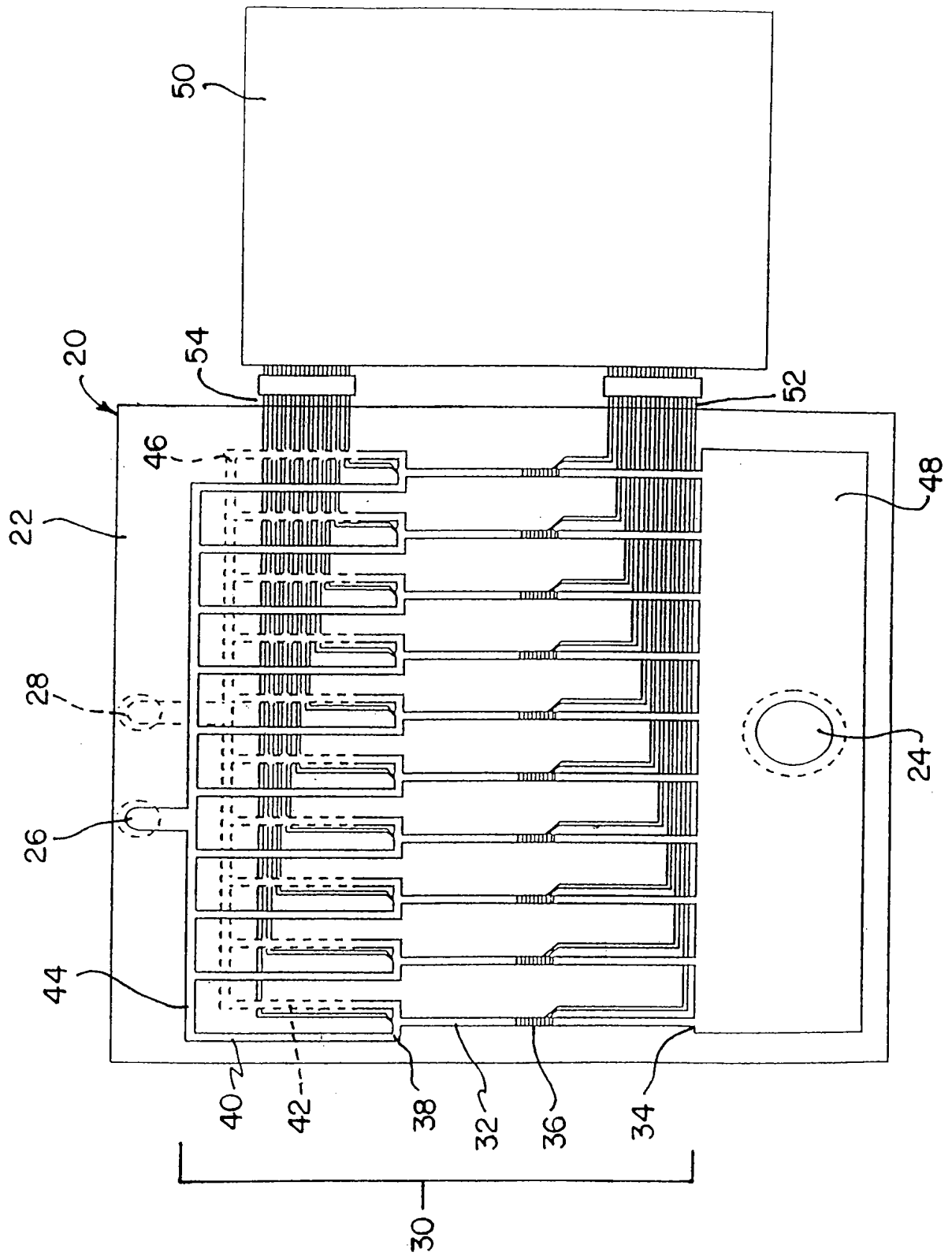


FIG. 2

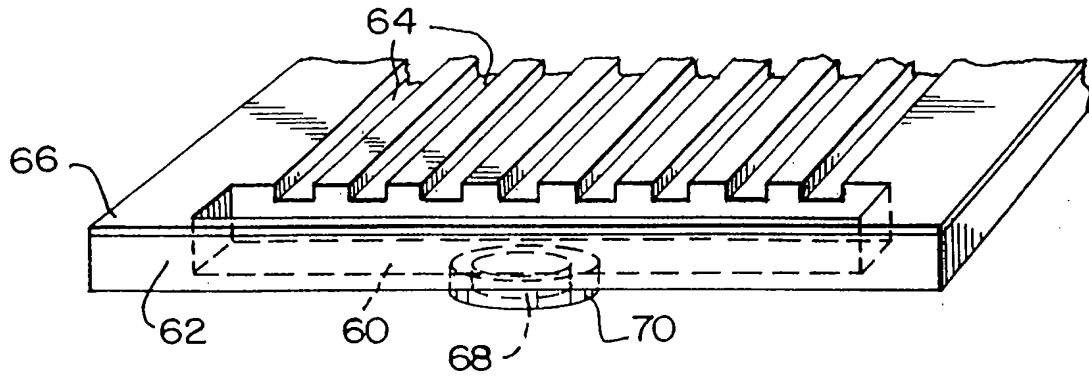


FIG. 3A

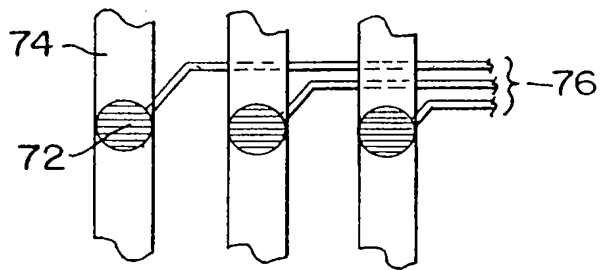


FIG. 3B

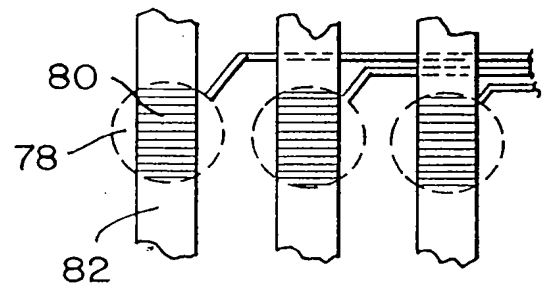


FIG. 4A

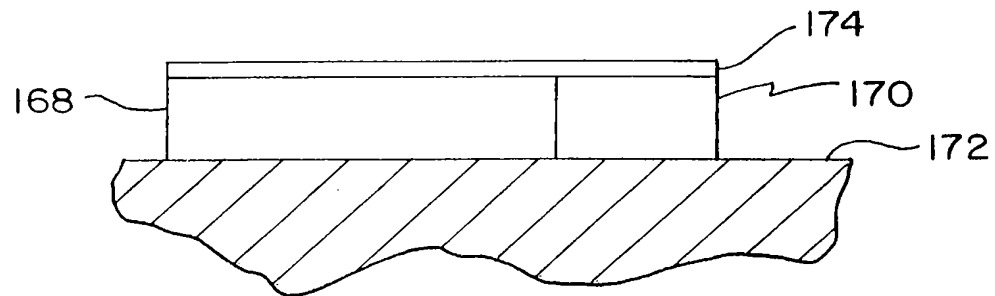


FIG. 4B

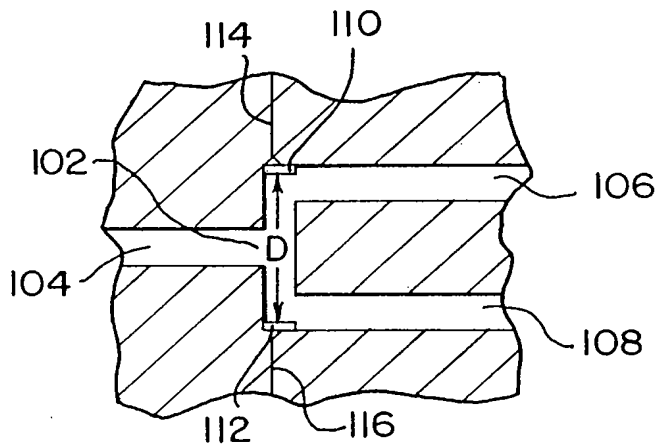
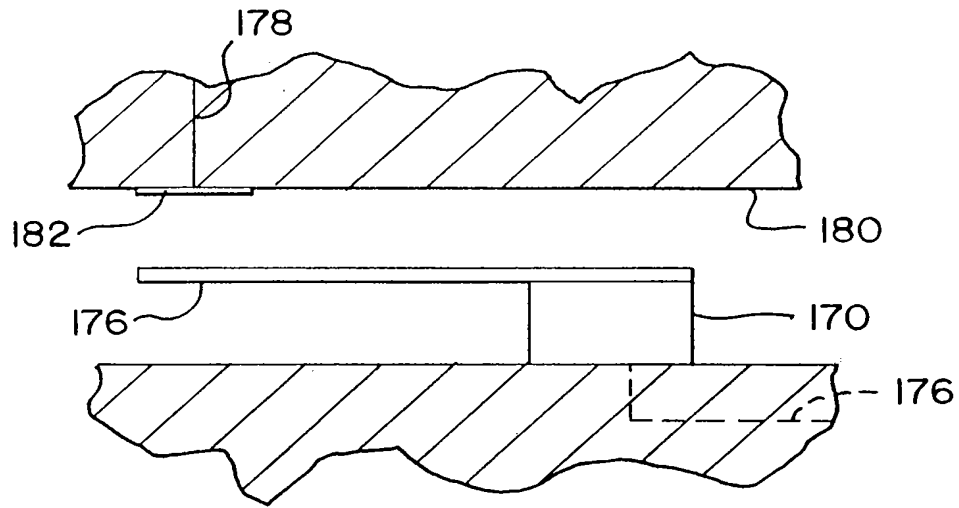


FIG. 5A

FIG. 5B

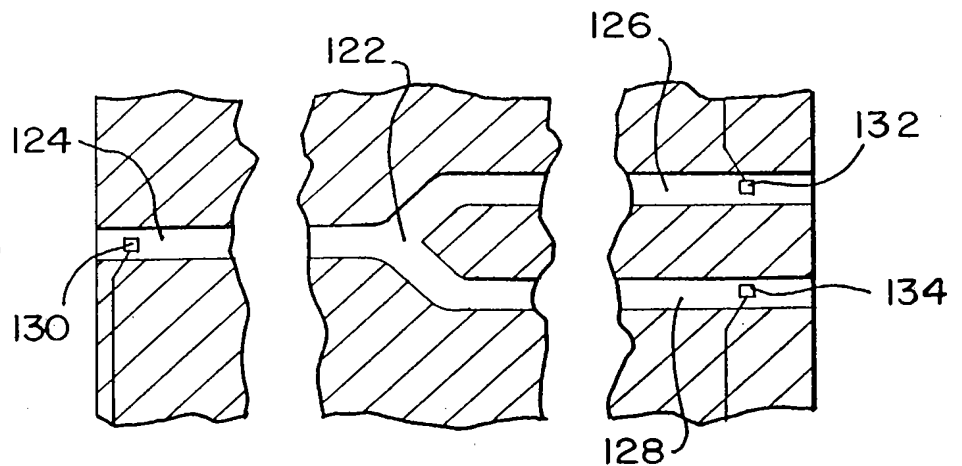


FIG. 5C

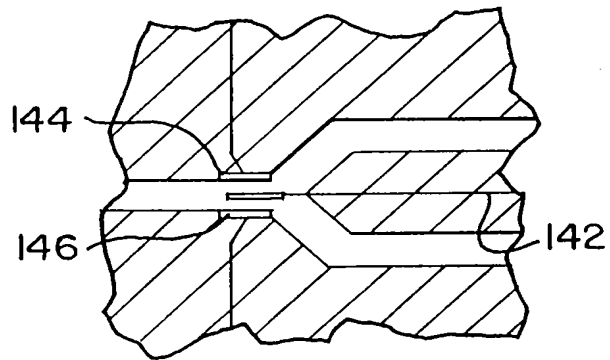


FIG. 5D

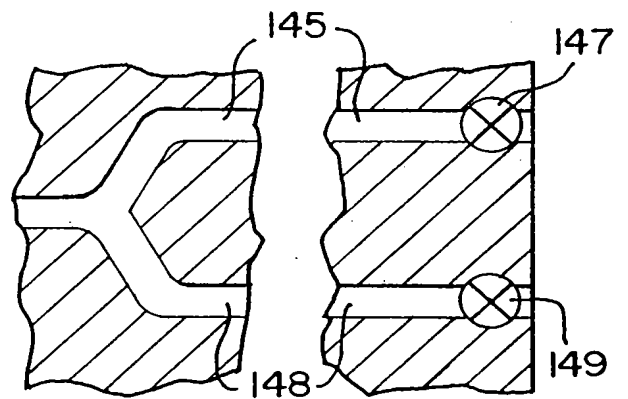
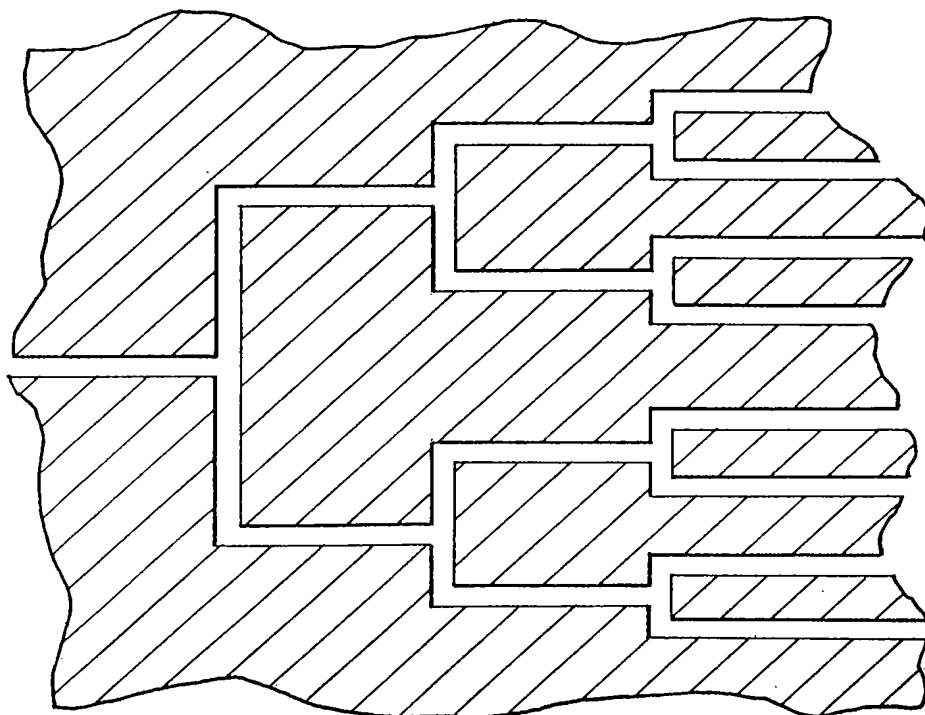


FIG. 6



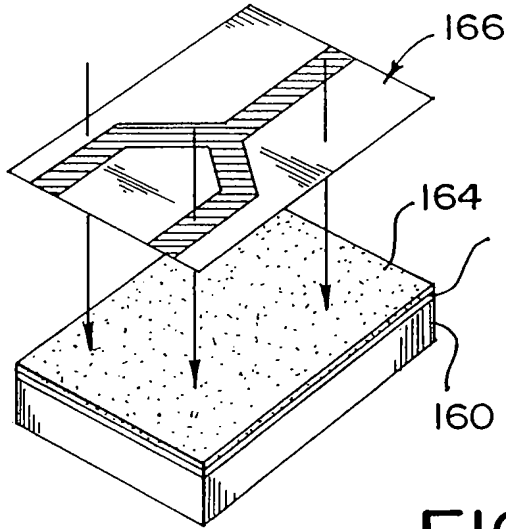
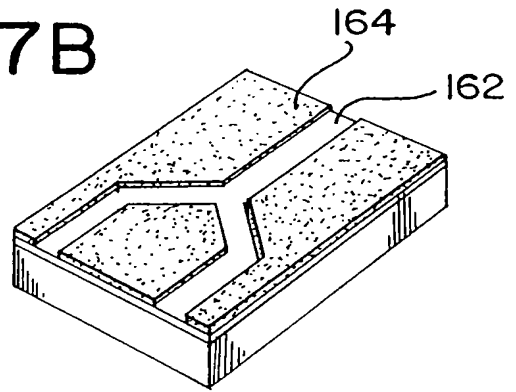


FIG. 7A

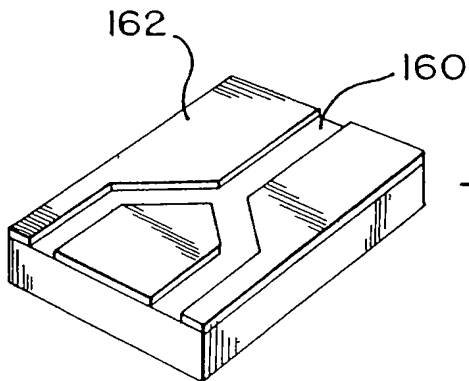
DEVELOP
& RINSE → TO FIG. 7B

FIG. 7B



TO FIG. 7C ← 1. ETCH SiO_2
2. REMOVE RESIST

FIG. 7C



ETCH Si → TO FIG. 7D

FIG. 7D

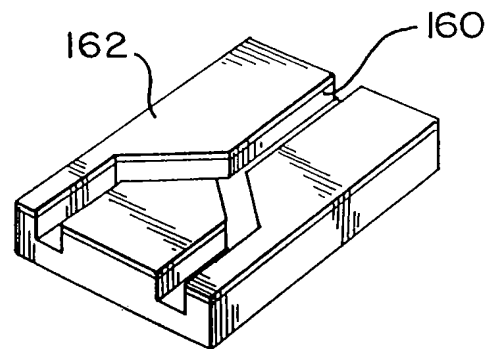
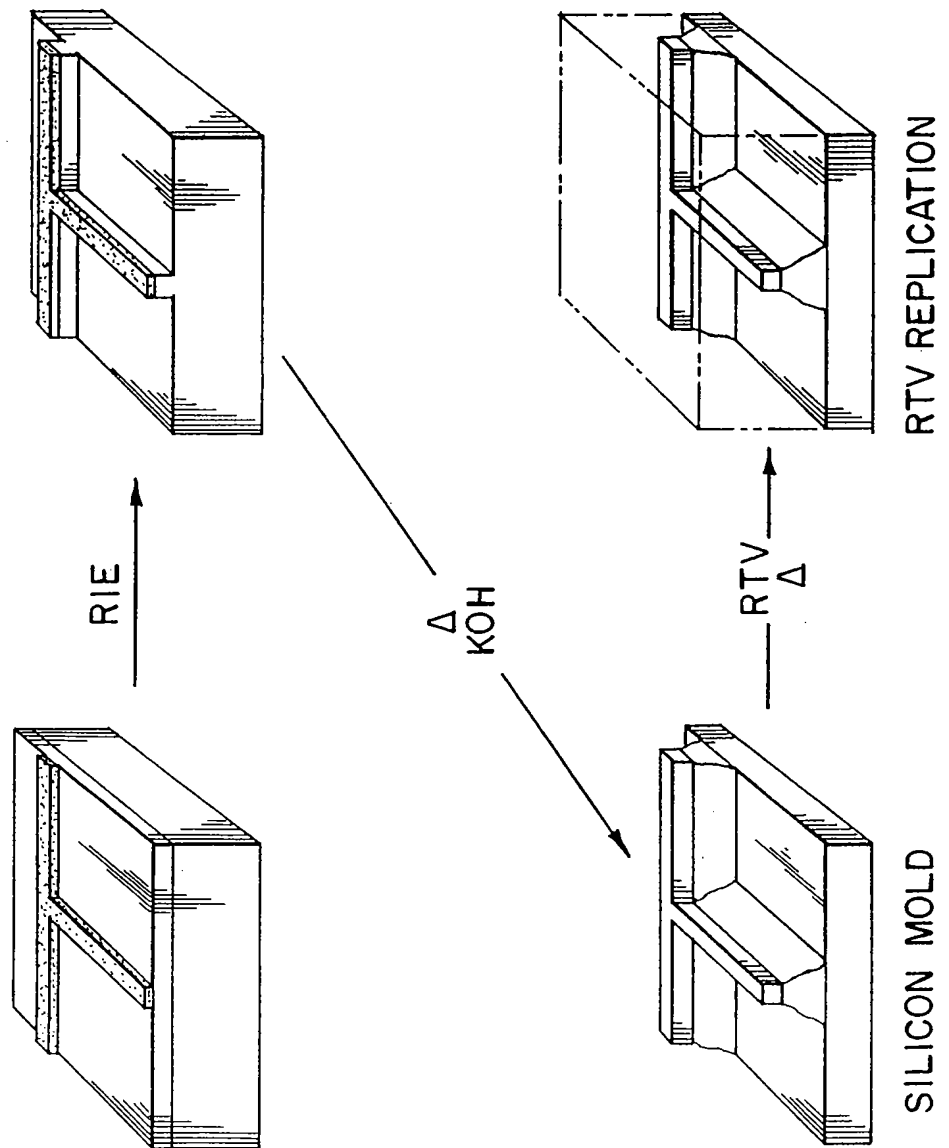


FIG. 8



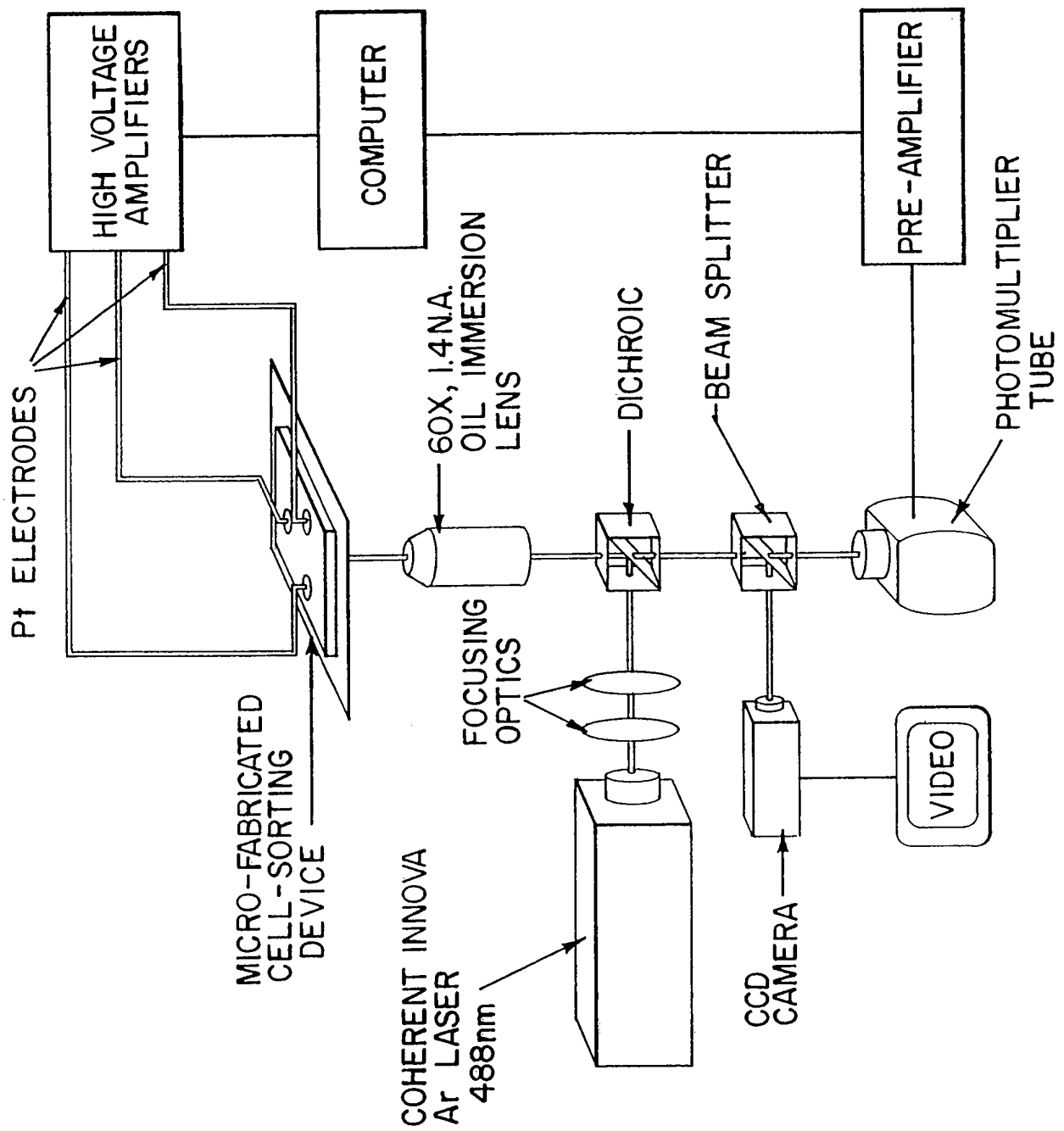


FIG. 9

FIG. 10

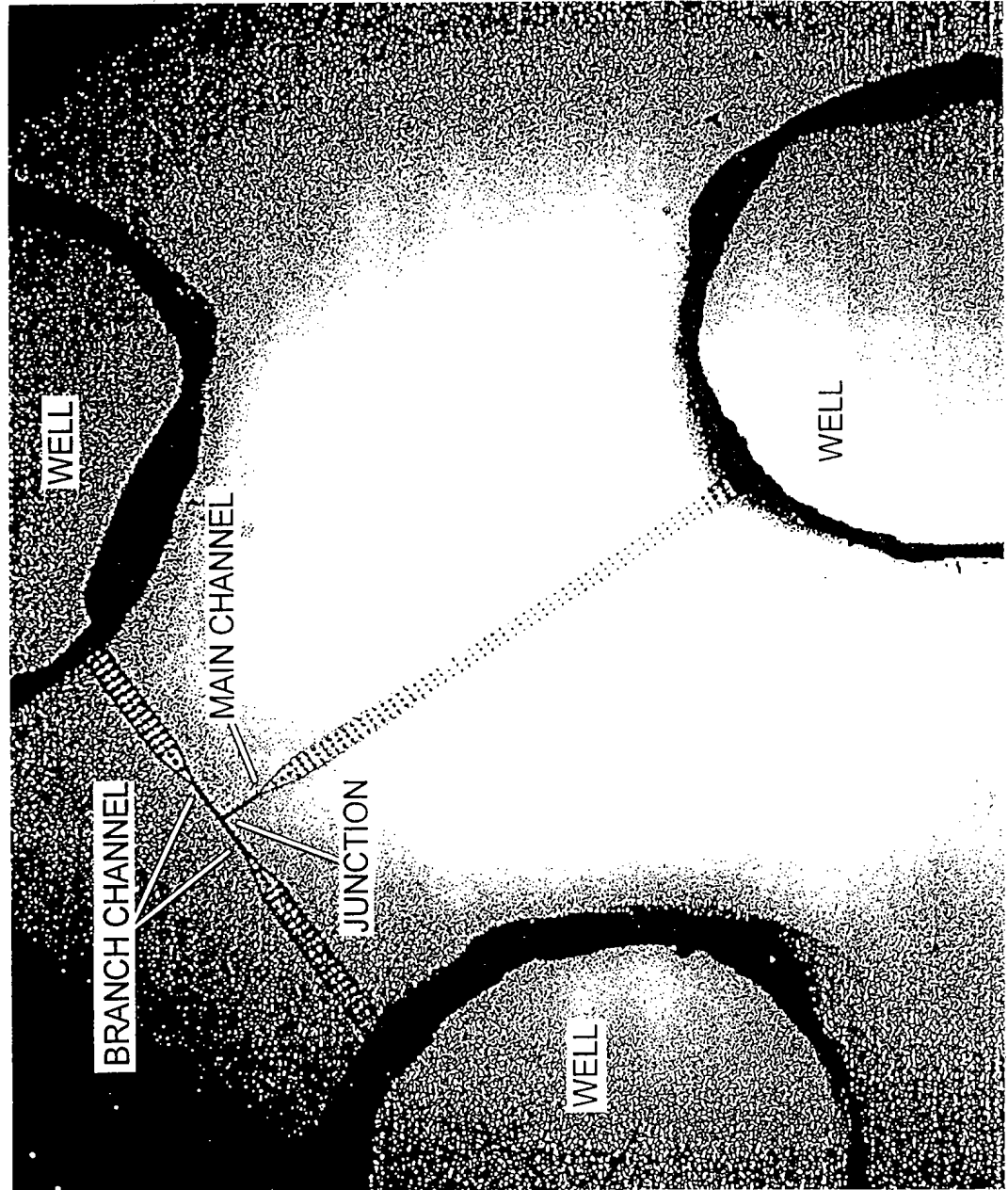


FIG. IIA

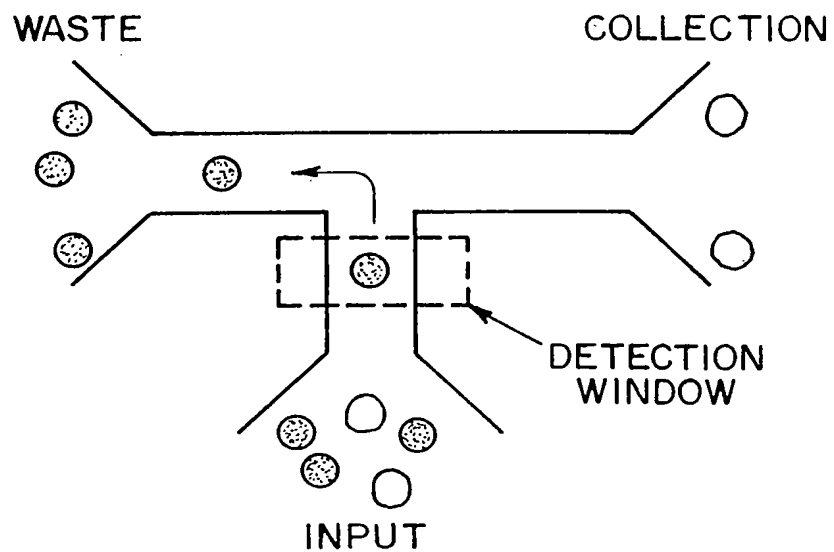


FIG. IIB

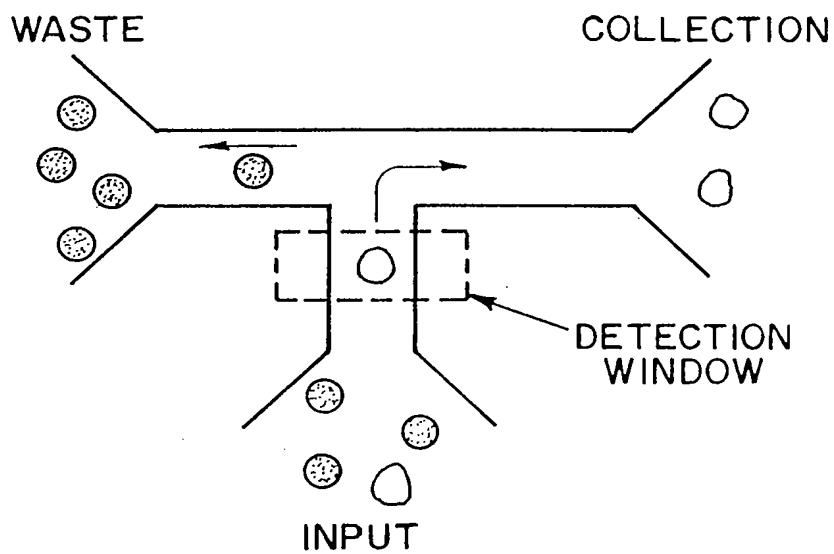


FIG. 12A

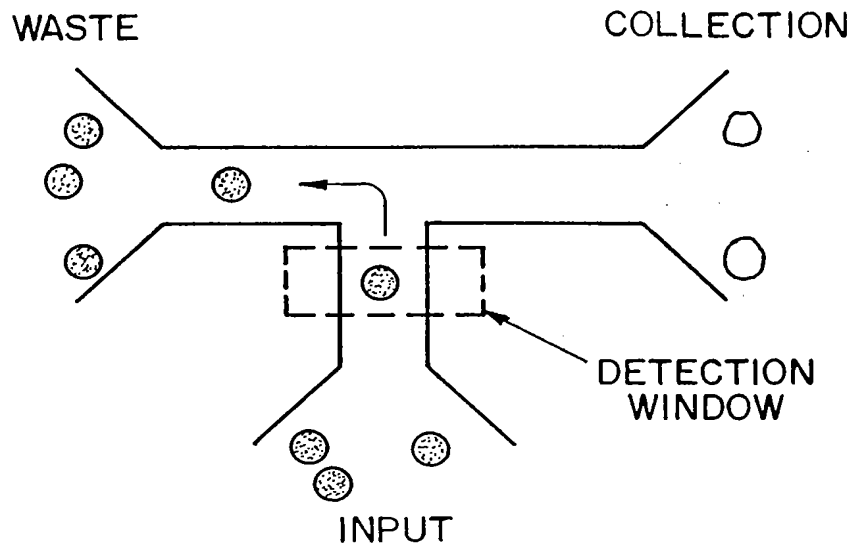
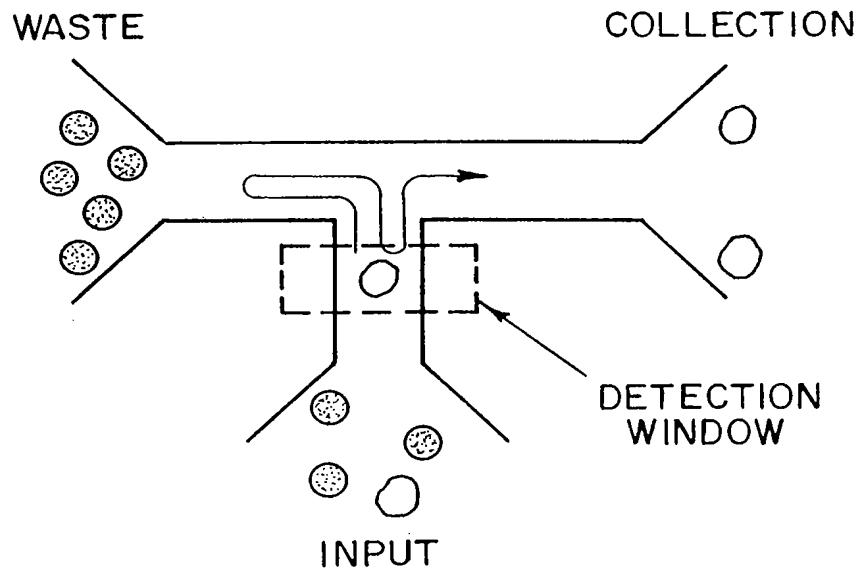


FIG. 12B



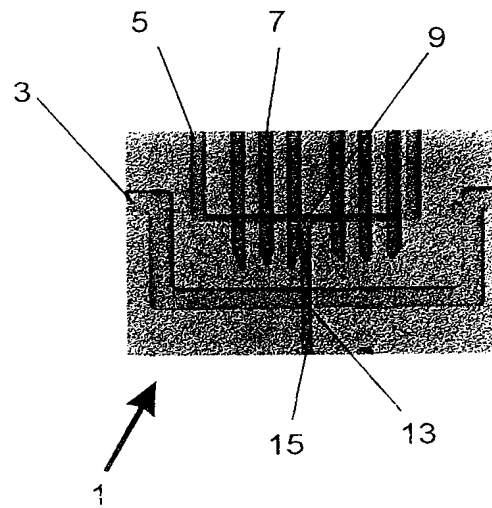


FIG. 13A

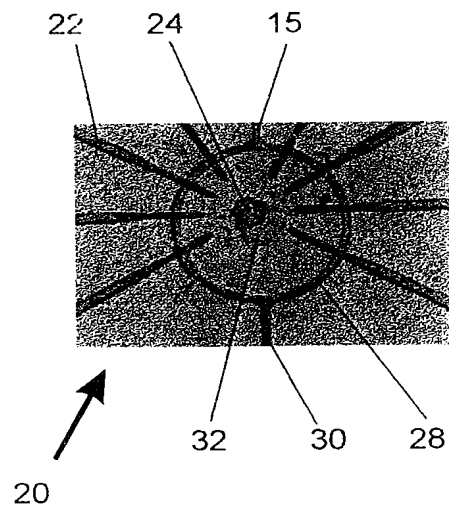
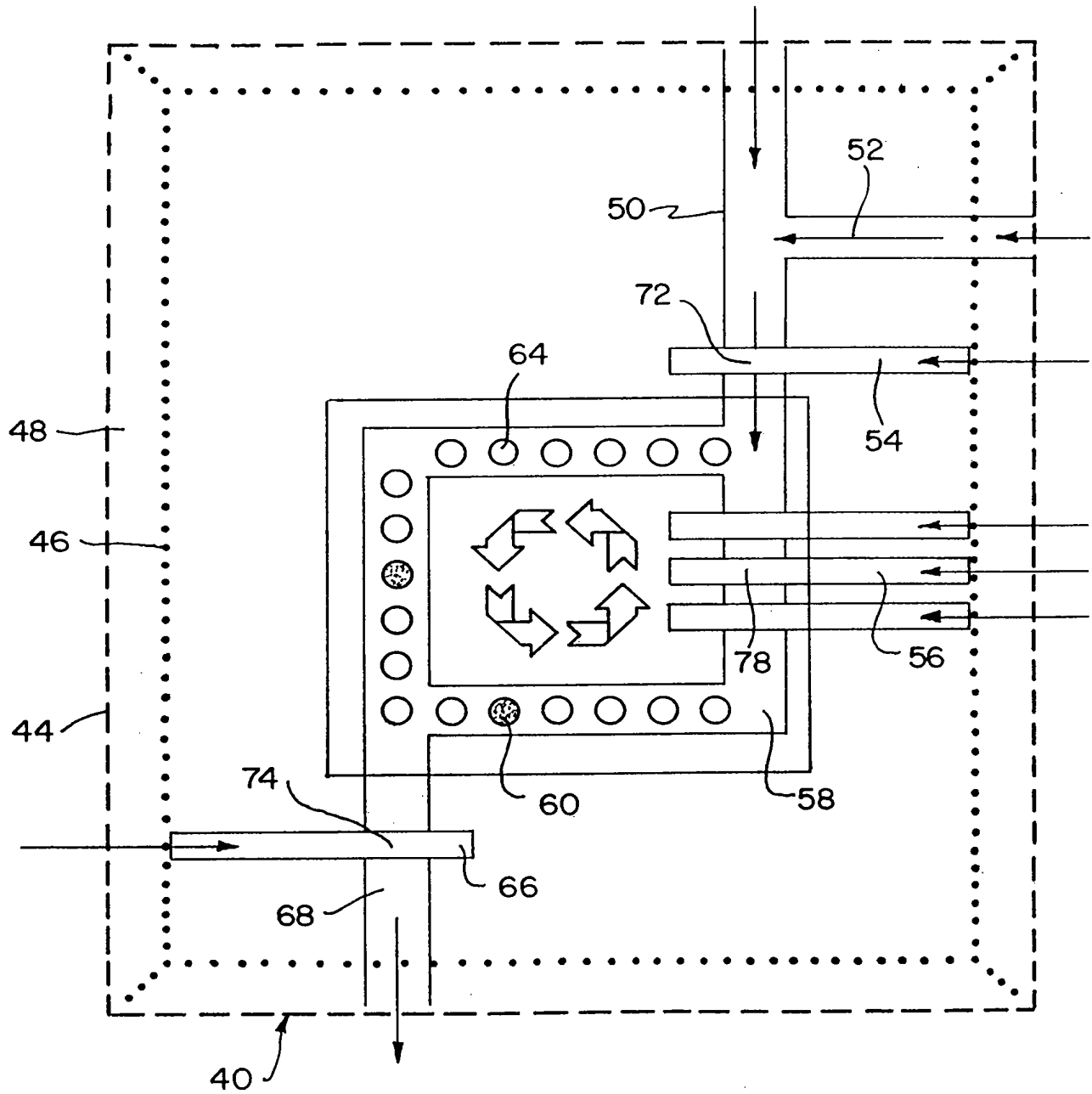


FIG. 13B

FIG. 14



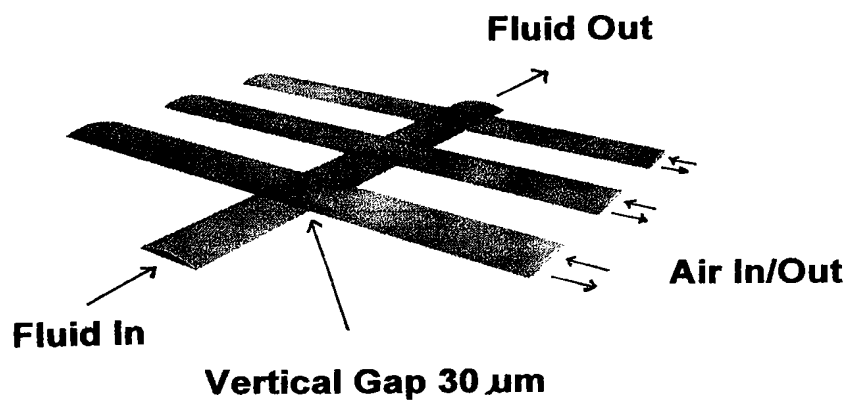


FIG. 15

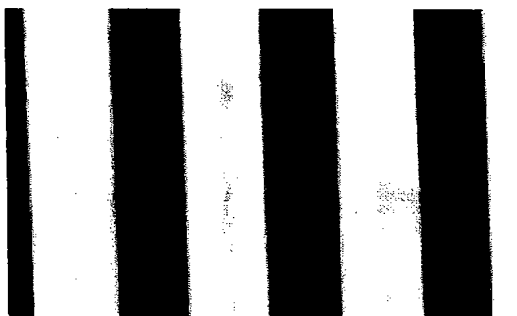


FIG. 16A

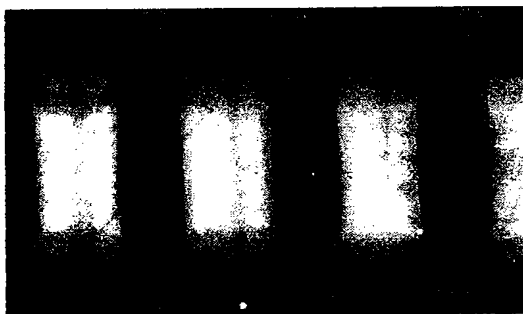


FIG. 16B

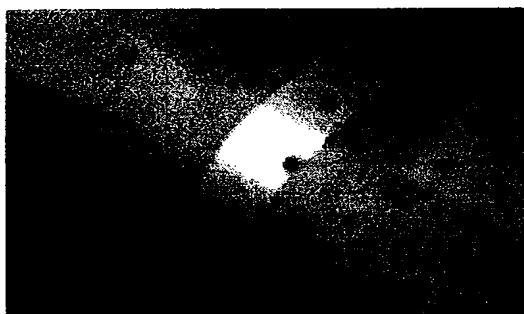


FIG. 16C

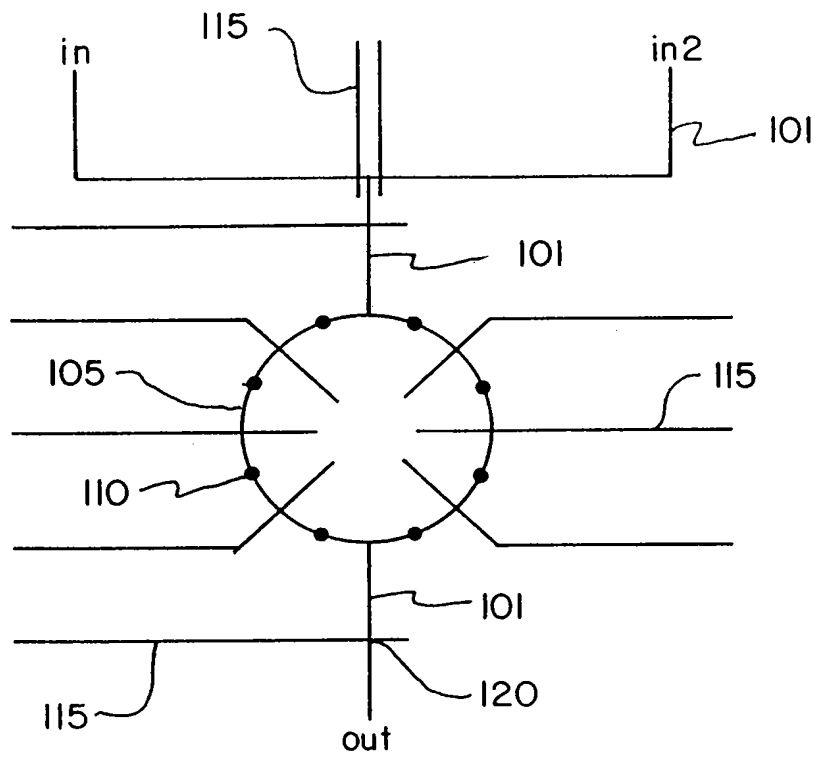


FIG. 17

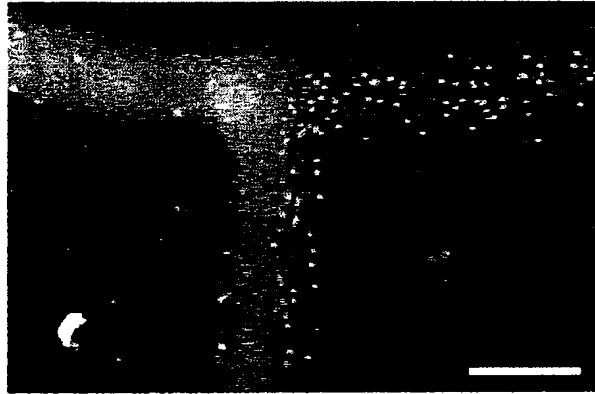


FIG. 18A

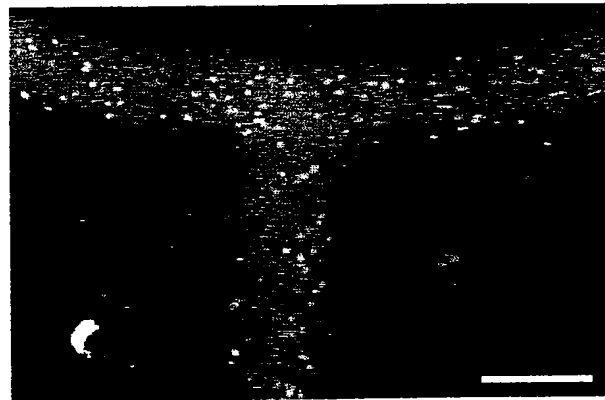


FIG. 18B



FIG. 19

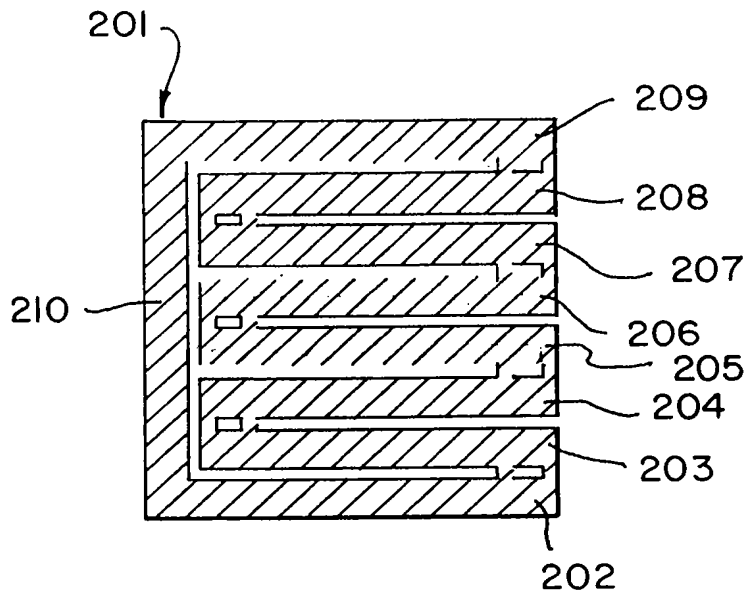


FIG. 20

FIG. 21A

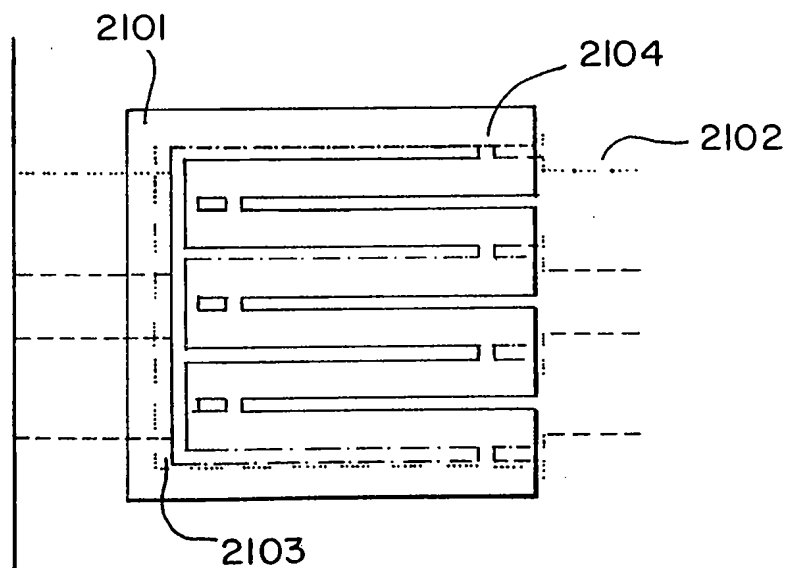
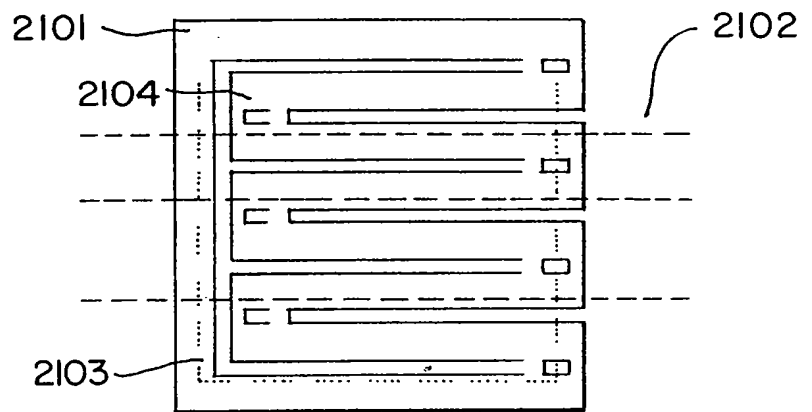


FIG. 21B

FIG. 22A

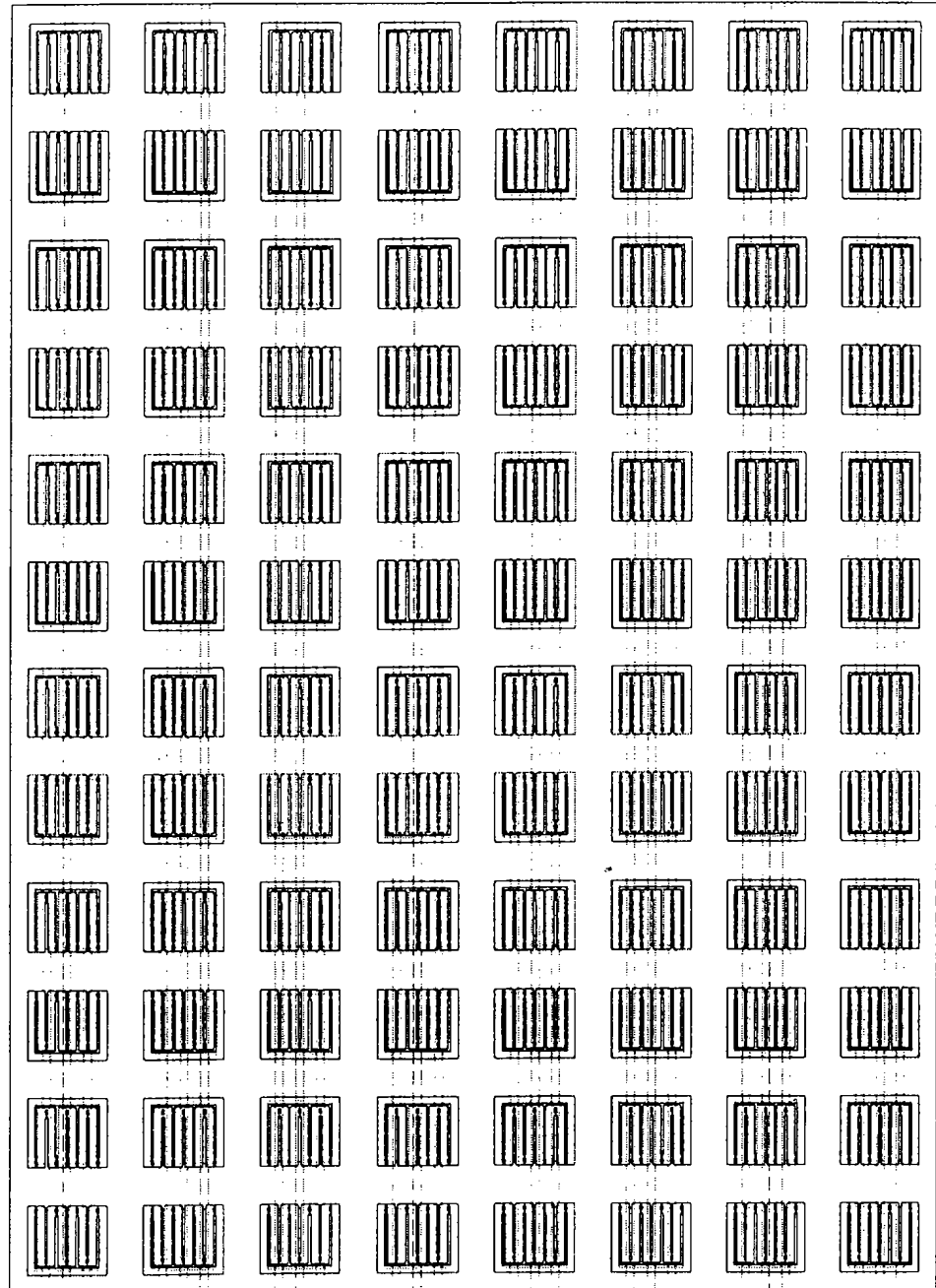


FIG. 22B

